of barium atoms located on said surface of said substrate material.

- 22. A semiconductor device comprising:
- a substrate;
- a barrier film comprised of a layer of elemental barium atoms on said substrate; and
 - a material on said barrier film
 - 23. A semiconductor device comprising:
 - a substrate;
- a barrier film comprising barium atoms having a thickness less than 100Å on said substrate; and
 - a material on said barrier film. --

REMARKS

Prior to examination, applicants request that the Examiner enter the foregoing amendment to the claims. An early action on the merits is respectfully requested.

Respectfully submitted,

Data.

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By

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